



Transaction Information

Tool ID	
Tool Status	Running Wafers
Location	
Wafer Size	300 mm
Fab Section	Etch
Tool Available Date	

General Product Information

Vendor Supplier	TEL
Model	TEL TACTRAS with VIGUS Ix BSP Chambers
Vintage	
Serial No	
Asset Description	Reactive Ion Etcher
Software Version	Ver. 6.80
CIM	GEM
Process	MHM Trench

Hardware Configuration

System Type	Description	Quantity
Factory Interface	FOUP	3
Options System	Nitrogen Purge Storage/Controller	1
Handler System	Loader Module YASKAWA Model NXC100 NLM W/S	1
Main System	VIGUS Ix BSP Chamber	6
Others	N/A	

Description	Quantity
PM5 - ESC	1

Description	Quantity
	0
PM5 - Foreline Pressure Switch(PS3)	1
PM5 ATCC Heater Controller	1
PM5 - ESC High Voltage Power Supply	1
	0